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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPL. NO. : 09/462,912 Confirmation No. 5646  
APPLICANTS: Shigeo MORIYAMA, et al.  
FILED : January 18, 2000  
FOR : POLISHING APPARATUS AND METHOD FOR PRODUCING  
SEMICONDUCTORS USING THE APPARATUS  
ART UNIT : 3723  
EXAMINER : Dung Van Nguyen  
DOCKET NO.: 29273/516  
CUSTOMER NO.: 23838

COMMISSIONER FOR PATENTS  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

SIR:

In response to the Final Office Action of July 7, 2004, the period for response having been extended herein to January 19, 2004 by payment of the requisite fee of \$980.00 for a Petition for Extension of Time Under 37 C.F.R. § 1.136(a), Applicants respectfully request that the Examiner reconsider his rejection in view of the remarks below. In addition, it is respectfully requested that the following clarifying amendment be entered to place this application in condition for allowance or better form for appeal.

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